Abstract

The specification discloses an apparatus for shaping part of the collective output beam of a plurality of semiconductor lasers, the plurality of semiconductor lasers being arranged to define a plurality of light-emitting areas and a plurality of non-light-emitting areas, and the semiconductor lasers having dimensions in X, Y and Z axes, wherein the Y axis defines a fast axis, the X axis defines a slow axis, and the Z axis defines an axis of propagation for the output beam. The apparatus comprises a first reflective member comprising at least a first reflective element positioned a fixed distance from the semiconductor lasers, the at least first reflective element adapted to deflect a first portion of the output beam in a first direction oriented at a first angle in the slow axis direction and at a second angle in the fast axis direction; and at least a second reflective member comprising at least a first reflective element positioned a fixed distance from the semiconductor lasers, the at least first reflective element of the second reflective member adapted to deflect the first portion of the output beam from the first direction to a second direction in the Z axis direction. By so shaping the output beam, the first portion of the output beam is oriented approximately parallel to the un-deflected remainder of the output beam, and the non-light-emitting areas are substantially eliminated from the output beam.